

LAMP2009 SESSION CHART

DAY-1: JUNE 29, 2009, MONDAY				DAY-2: JUNE 30, 2009, TUESDAY				DAY-3: JULY 1, 2009, WEDNESDAY				DAY-4: JULY 2, THURSDAY							
A M					ROOM 1 (3A)	ROOM 2 (2A)	ROOM 3 (2B)	ROOM 4 (3B)	ROOM 1 (3A)	ROOM 2 (2A)	ROOM 3 (2B)	ROOM 4 (3B)	ROOM 1 (3A)	ROOM 2 (2A)	ROOM 3 (2B)	ROOM 4 (3B)			
					LPM 3-1	LPM 3-2: SP L3	LPM 3-3	HPL-3	LPM 6-1	LPM 6-2: SP L1	LPM 6-3	HPL-6	LPM 9-1	LPM 9-2: SP L2	LPM 9-3	HPL-9			
					Ultrafast Laser Processing - Fundamentals and Dignostics (9:00-10:50) 110 min.	Laser Synthesis of Nanomaterials (I) (9:00-10:50) 110 min.	Lithography and Photo-polymerization (9:00-10:50) 110 min.	Removal (9:00-10:40) 100 min.	Ultrafast Laser Processing - Nano-structuring (9:00-11:00) 120 min.	Tailoring of Mechanical Properties (9:00-10:50) 110 min.	Systems, Optics and Applications of VUV and X-ray (9:00-10:40) 100 min.	Welding 3 (9:00-10:50) 110 min.	Femtosecond Laser Systems (9:00-10:20) 80 min.	Spatial and Temporal Beam Manipulation for High Throughput Laser Processing (9:00-10:30) 90 min.	Biomedical Applications (9:00-10:20) 80 min.	Micro Processing (9:00-10:20) 80 min.			
COFFEE BREAK (Sponsored by Ophir Japan, Ltd.)				COFFEE BREAK (Sponsored by Ophir Japan, Ltd.)				COFFEE BREAK (Sponsored by Ophir Japan, Ltd.)				COFFEE BREAK (Sponsored by Ophir Japan, Ltd.)							
OPENING REMARK (10:00-10:10) PLENARY SESSION (Sponsored by Tada Electric Co., Ltd.) (10:10-12:10) 40 min x3 talks= 120min. ROOM 1 (3A)				SHORT PRESENTATION for POSTER SESSION (11:10-12:10) 60 min. ROOM 1 (3A) & ROOM 4 (3B)				SHORT PRESENTATION for POSTER SESSION (11:10-12:10) 60 min. ROOM 1 (3A) & ROOM 4 (3B)				LPM 10-1	LPM 10-2: SP L2	LPM 10-3	HPL-10	Practical and Industrial Applications I (10:40-12:10) 90 min	Beam Manipulation for Spatial Control and Optimization (10:50-12:20) 90 min	Fundamentals and Analysis (10:40-12:20) 100 min	Trend of Laser Processing (10:40-12:10) 90 min.
LUNCH TIME				POSTER SESSION & LUNCH TIME (Sponsored by Coherent Japan, Inc.) (12:20-13:50) 90 min. Exhibition Hall on 1st Floor				POSTER SESSION & LUNCH TIME (Sponsored by Coherent Japan, Inc.) (12:20-13:50) 90 min. Exhibition Hall on 1st Floor				LUNCH TIME							
ROOM 1 (3A)	ROOM 2 (2A)	ROOM 3 (2B)	ROOM 4 (3B)	ROOM 1 (3A)	ROOM 2 (2A)	ROOM 3 (2B)	ROOM 4 (3B)	ROOM 1 (3A)	ROOM 2 (2A)	ROOM 3 (2B)	ROOM 4 (3B)	ROOM 1 (3A)	ROOM 2 (2A)	ROOM 3 (2B)	ROOM 4 (3B)				
LPM 1-1	LPM 1-2: SP L3	LPM 1-3	HPL-1	LPM 4-1	LPM 4-2: SP L3	LPM 4-3	HPL-4	LPM 7-1	LPM 7-2: SP L1	LPM 7-3	HPL-7	LPM 11-1	LPM 11-2	LPM 11-3	HPL-11				
Laser Micro-Welding (14:00-16:00) 120 min.	Laser Nanopatterning (I) (14:00-15:50) 110 min.	Film Growth and Crystallization (14:00-16:00) 120 min.	Fundamentals (14:00-15:50) 110 min.	Ultrafast Laser Processing - Transparent Materials Processing (14:00-15:50) 110 min.	Laser Synthesis of Nanomaterials (II) (14:00-15:50) 110 min.	Laser Direct Write - Fundamentals and Micro/Nano-fabrication (14:00-15:50) 110 min.	Welding 1 (14:00-15:50) 110 min.	Ultrafast Laser Processing - Micromachining (14:00-15:40) 100 min..	Laser Crystallization and Semiconductor Processing (14:00-15:50) 110 min.	Advanced Lasers for Microprocessing (14:00-15:40) 100 min.	Surface Modification 1 (14:00-15:30) 90 min.	Practical and Industrial Applications II (13:40-15:20) 100 min.	Versatile Beam Shaping for Industrial Applications (13:50-15:20) 90 min.	Media Assisted Processing (13:40-15:30) 110 min.	Welding 4 (13:50-15:20) 90 min.				
COFFEE BREAK (Sponsored by Ophir Japan, Ltd.)				COFFEE BREAK (Sponsored by Ophir Japan, Ltd.)				COFFEE BREAK (Sponsored by Ophir Japan, Ltd.)				COFFEE BREAK (Sponsored by Ophir Japan, Ltd.)							
LPM 2-1	LPM 2-2: SP L3	LPM 2-3	HPL-2	LPM 5-1	LPM 5-2: SP L3	LPM 5-3	HPL-5	LPM 8-1	LPM 8-2: SP L1	LPM 8-3	HPL-8	JOINT SESSION Crossover Regions of LPM and HPL (15:40-16:40) 60 min. ROOM 1 (3A)							
Fine Cutting and Dicing (16:20-18:00) 100 min.	Laser Nanopatterning (II) (16:20-18:00) 100 min.	Micromachining and Patterning (16:20-18:00) 100 min.	Monitoring (16:20-18:00) 100 min.	Ultrafast Laser Processing - 3D Fabrication (16:10-18:20) 130min.	Laser Synthesis of Nanomaterials (III) (16:20-18:00) 100 min.	Laser Direct Write - Fabrication of Microdevices and Systems (16:10-18:20) 130 min.	Welding 2 (16:10-18:10) 120 min.	Ultrafast Laser Processing - Practical Applications (16:00-18:10) 130 min.	Chemical and Biological Properties of Surfaces (16:10-18:10) 120 min.	Nano-technology (16:00-18:10) 130 min.	Surface Modification 2 (16:10-18:10) 120 min.	Outstanding Paper Awards (16:40-) CLOSING REMARK (-17:00)							
TRANSPORT TO BANQUET								BANQUET at "KOBE KACHO EN" (神戸花鳥園) (Sponsored by Megaopto Co., Ltd & e.x. press) Two stations away from "Shimin Hiroba"Sta. of Kobe Portliner Address: 7-1-9 Minami-machi, Minato-jima, Cyuo-Ku, Kobe TEL: 078-302-8899 FAX: 078-302-8222 (19:00-21:00)											

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